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TECHNOLOGY CENTER 3700

PATENT
CASE NO. 7103/30-1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Homayoun Talieh et al.

Serial No.: 08/853,323

Filed: May 8, 1997

For: LINEAR POLISHER AND
METHOD FOR
SEMICONDUCTOR WAFER
PLANARIZATION

Examiner: G. Nguyen

Group Art Unit: 3723

RESPONSE AND AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated September 21, 1999 please enter the following amendment and consider the following remarks: